

3-13-02
PB

Docket: 740819-723

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of
Masahiro ISHIDA)
Japanese Priority Application No. 2001-019549)
Japanese Priority Date: January 29, 2001) Attn: Applications
For: METHOD OF MANUFACTURING) Branch
NITRIDE SEMICONDUCTOR SUBSTRATE)
Date: January 2, 2001

1000 U.S. PRO
10/032563
01/02/02

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents and Trademarks
Washington, D.C. 20231

Sir:

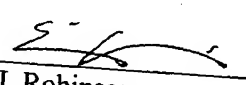
In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

At least some of the references listed on PTO Form-1449 are discussed in the specification of the present application.

Copies of these references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

Japanese Patent No. 3091593 was laid open to public inspection under Japanese Patent Laid Open Gazette No. 6-216409, and an English language Abstract of 06-216409 is enclosed.

Respectfully submitted,


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